

Title (en)

A WAFER BUFFER STATION AND A METHOD FOR A PER-WAFER TRANSFER BETWEEN WORK STATIONS

Title (de)

HALBLEITERSCHEIBEN-BUFFERSTATION UND VERFAHREN ZUM EINZELTRANSPORT VON HALBLEITERPLÄTTCHEN ZWISCHEN ARBEITSPLÄTZEN

Title (fr)

POSTE TAMPON POUR PLAQUETTES ET PROCEDE DE TRANSFERT PLAQUETTE PAR PLAQUETTE ENTRE DES POSTES D'USINAGE

Publication

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Application

EP 99921607 A 19990430

Priority

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Abstract (en)

[origin: WO9960614A1] A buffer station is disclosed, for a "per wafer" transfer of wafers between work stations. The wafers are retrieved from the pod by a track robot at a first work station and are processed. When the processing at the first work station is completed, the track robot takes the wafer and, rather than returning it to the pod, places the wafer in the buffer station. When the second work station is ready to accept the wafer, its track robot retrieves the wafer from the buffer station and inserts it into the second work station for processing. When processing is completed at the second work station, the track robot inserts the wafer into a pod located at the second work station.

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H01L 21/00

IPC 8 full level

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CPC (source: EP KR)

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